

4-point probe - CMT-SR2000N	103	Metrology
Aligning and Assembling Machine	509	LCD Processing equipment
Alignment microscope	242	Metrology
Anneal - CCC #3-1 Al. anneal	705.1	Thermal processing
Anneal - CCC #3-2 Au anneal	705.2	Thermal processing
Anneal - CCC #3-3 Hi temp anneal	705.3	Thermal processing
Branson/IPC Plasma Strip	1169	Plasma equipment
Buffing machine	507	LCD Processing equipment
CAIBE Ion Beam System - Oxford Ionfab	417	Plasma equipment
Critical Point Dryer	1170	Freeze drying
DI Nanoscope SPM	111	Metrology
Dicing saw - Disco DAD3350	1011	Dicing/scribing/polishing
Dicing saw - Loadpoint Microace 3+	1008	Dicing/scribing/polishing
Doping - CCC #2-1 Boron doping	706.1	Thermal processing
Doping - CCC #2-2 Boron drive in	706.2	Thermal processing
Doping - CCC #2-3 Phosphorus doping	706.3	Thermal processing
Doping - CCC #2-4 Phosphorus drive in	706.4	Thermal processing
e-beam evaporator - Lesker Spectros	434	Evaporation
EBL - JEOL JBX-5DII	264	E-beam lithography
EBL - JEOL JBX-9300FS	217	E-beam lithography
Electroplating equipment - III/V Photoli	626	Wet Process Benches
Ellipsometer - Rudolph AutoEL-II	105	Metrology
Ellipsometer - Sagax Iscoscope	104	Metrology
Evaporator - AVAC HVC600	420	Evaporation
Evaporator - Balzers (Al)	1101	Evaporation
Evaporator - Balzers System BAK600	514	Evaporation
Evaporator - Edwards HPTS	425	Evaporation
Evaporator - Opto	408	Evaporation
Furnace - Hereaus T5028	415	Special furnaces/substrate bonders
Furnace Boron doping - Tempress	1102.2	Thermal processing
Furnace for "General use" - Tempress	1105	Thermal processing
Furnace for dry oxidation - Tempress	1104.2	Thermal processing
Furnace general annealing - Tempress	1104.3	Thermal processing
Furnace Phosphorous doping - Tempress	1102.1	Thermal processing
Furnace Silicon Anneal - Tempress	1102.3	Thermal processing
Furnace Wet oxidation - Tempress	1104.1	Thermal processing
Glue Dispensing System - Asymtek model type 402	515	LCD Processing equipment
High temperature furnace - Thermolyne	713	Special furnaces/substrate bonders
Inspection Microscope - Olympus AH3 (Vanox)	102	Metrology
Inspection Microscope - Olympus BX51	1113	Metrology
Inspection Microscope - Olympus MX40	106	Metrology
Inspection Microscope - Olympus MX40	635	Metrology
Inspection Microscope - Olympus MX40	630	Metrology
Inspection Microscope - Olympus MX50	125	Metrology
Inspection Microscope - Olympus MX50	266	Metrology
IR Wafer Inspection System	127	Metrology
Laser ablation - Compex 110	1140	Laser ablation
Laser ablation - Compex 205	1141	Laser ablation
LB monolayer deposition system	502	LCD Processing equipment
LPCVD - CCC #4-1 LP-LTO	708.1	Thermal processing
LPCVD - CCC #4-2 LP-TEOS	708.2	Thermal processing
LPCVD - CCC #4-3 LP-Silicon nitride	708.3	Thermal processing
LPCVD - CCC #4-4 LP-Polysilicon	708.4	Thermal processing
Macro photo system	118	Metrology
Mask aligner - KS MA/BA 6	205	Photolithography
Mask aligner - KS MJB2	222	Photolithography
Mask aligner - KS MJB3-DUV	224	Photolithography
Mask aligner - KS MJB3-UV 400, #1	210	Photolithography
Mask aligner - KS MJB3-UV 400, #2	268	Photolithography
Mask aligner - Projection print aligner	1117	Photolithography
MBE-system - EPI 930	806	Evaporation
Nanoimprint Lithography Unit	267	Nanoimprint lithography
Ovens for Solid Dopant Sources	1114	Special furnaces/substrate bonders
Oxidation - CCC #1-1 Dry oxidation	707.1	Thermal processing
Oxidation - CCC #1-2 Wet oxidation	707.2	Thermal processing
Oxidation - CCC #1-3 Wet oxidation	707.3	Thermal processing
Oxidation furnace	411	Special furnaces/substrate bonders
PECVD - STS	303	CVD equipment
Photolithography Stepper - ASML PAS 2500	201	Photolithography

Plasma etch - STS ICP	307	Plasma equipment
Polishing machine - Logitech PM5	1006	Dicing/scribing/polishing
Probe Station - KS PM5	123	Metrology
Process bench (Acid)- Etch baths	652	Wet Process Benches
Process bench - Chemical preparation (Acid)	1309	Wet Process Benches
Process bench - Chemical preparation (Solvent)	1302	Wet Process Benches
Process bench - Developer baths	208	Wet Process Benches
Process bench - Developer III/V and nano	220	Wet Process Benches
Process bench - Developer spinner BLE De	204	Wet Process Benches
Process bench - e-beam resist development	256	Wet Process Benches
Process bench - e-beam resist spinner and	255	Wet Process Benches
Process bench - Electroplating & Acid work	621	Wet Process Benches
Process bench - General (Solvent) work	625	Wet Process Benches
Process bench - General cleaning	1002	Wet Process Benches
Process bench - General Silicon work(Acids)	653	Wet Process Benches
Process bench - General Silicon work(Acids)	654	Wet Process Benches
Process bench - General silicon work, 11	1112	Wet Process Benches
Process bench - General Silicon work, 11	1110	Wet Process Benches
Process bench - General Solvent work	655	Wet Process Benches
Process bench - General work, solvents	622	Wet Process Benches
Process bench - Hot baths & Acid work	623	Wet Process Benches
Process bench - Hotplate and ovens	260	Wet Process Benches
Process bench - Hotplates and ovens LCD	501	Wet Process Benches
Process bench - Liftoff & Solvent work	624	Wet Process Benches
Process bench - Manual development	1118	Wet Process Benches
Process bench - Manual development and H	253	Wet Process Benches
Process bench - Mask developer and etch	254	Wet Process Benches
Process bench - Mask spincoater and SB h	212	Wet Process Benches
Process bench - Megasonic bath and Solvent	628	Wet Process Benches
Process bench - Photoresist development	251	Wet Process Benches
Process bench - Photoresist spinner and	219	Wet Process Benches
Process bench - Polishing preparation/cleaning	1001	Wet Process Benches
Process bench - Preparation III/V, II/VI	627	Wet Process Benches
Process bench - Preparation III/V, II/VI	629	Wet Process Benches
Process bench - Resist (Headway) spinner	1116	Wet Process Benches
Process bench - Resist spinner III/V and	218	Wet Process Benches
Process bench - Solvents and ultrasonic	620	Wet Process Benches
Process bench - Wafer cleaning(Acid), 651	651	Wet Process Benches
Process bench - Wafer cleaning, 1109	1109	Wet Process Benches
Process bench - Wet etch KOH	609	Wet Process Benches
Process bench - Wet etch TMAH	608	Wet Process Benches
Process bench - Wet lithography & ITO et	505	Wet Process Benches
Profilometer - Tencor Alfastep 500	230	Metrology
Profilometer - Tencor P2	101	Metrology
Pulsed Laser Deposition - Calas System	1141.1	Laser ablation
Pulsed Laser Deposition - Small System	1140.1	Laser ablation
Pulsed Laser Deposition - Twin System	1140.2	Laser ablation
Quartz tube cleaner	601	Wet Process Benches
Quartz tube stocker	661	Wet Process Benches
Resist spinner - KS RC-8	206	Photolithography
RIBE Ion beam System - Oxford Ionfab 300	412	Plasma equipment
RIE - Plasma Therm Batchtop PE/RIE m/95	419	Plasma equipment
RIE - Plasma Therm Batchtop RIE m/91	418	Plasma equipment
RIE - Vacutec	1167	Plasma equipment
RIE/CVD - Oxford Plasmalab System 100	404	Plasma equipment
RPECVD reactor	1127	CVD equipment
RTA Opto	410	RTP
RTP - AG Heatpulse 610 (High temp)	433	RTP
RTP - AG Heatpulse 610 (Low temp)	431	RTP
RTP - STEAG SHS 100M	402	RTP
Scriber (Hard materials)	1009	Dicing/scribing/polishing
Scriber (Soft materials)	413	Dicing/scribing/polishing
Scriber - glass substrates	508	Dicing/scribing/polishing
SEM - JEOL JSM-6301F	110	Metrology
Sputter - Balzers PLS 550	407	Sputtering
Sputter - NORDIKO 2000	401	Sputtering
Sputter - Pfeiffer SLS	426	Sputtering
Stereomicroscope - Olympus SZH-10	126	Metrology
Stereomicroscope - Olympus SZX-12	642	Metrology
Stereomicroscope - Olympus SZX-12	638	Metrology
Stereomicroscope - Olympus SZX-9	1126	Metrology
Stereomicroscope - Olympus SZX-9	244	Metrology
Stereomicroscope - Olympus SZX9	1010	Metrology

Substrate bonder - Suss SB6	269	Special furnaces/substrate bonders
Substrate cleaner, Suss CL6	270	Special furnaces/substrate bonders
TePla 300PC Microwave Plasma Strip	228	Plasma equipment
UHV Evaporator - Varian VT 118 UHV	406	Evaporation
Wash-up - Fumehood & lab dishwasher - Na	234	Wet Process Benches
Wash-up - Fumehood (Acid) III/IV and nano	660	Wet Process Benches
Wash-up - Fumehood Acid III/IV Photolitho	236	Wet Process Benches
Wash-up - Fumehood and lab dishwasher -	656	Wet Process Benches
Wash-up - General work	659	Wet Process Benches
Wedge bonder - West Bond 7400B	1171	Packaging/Wire bonding